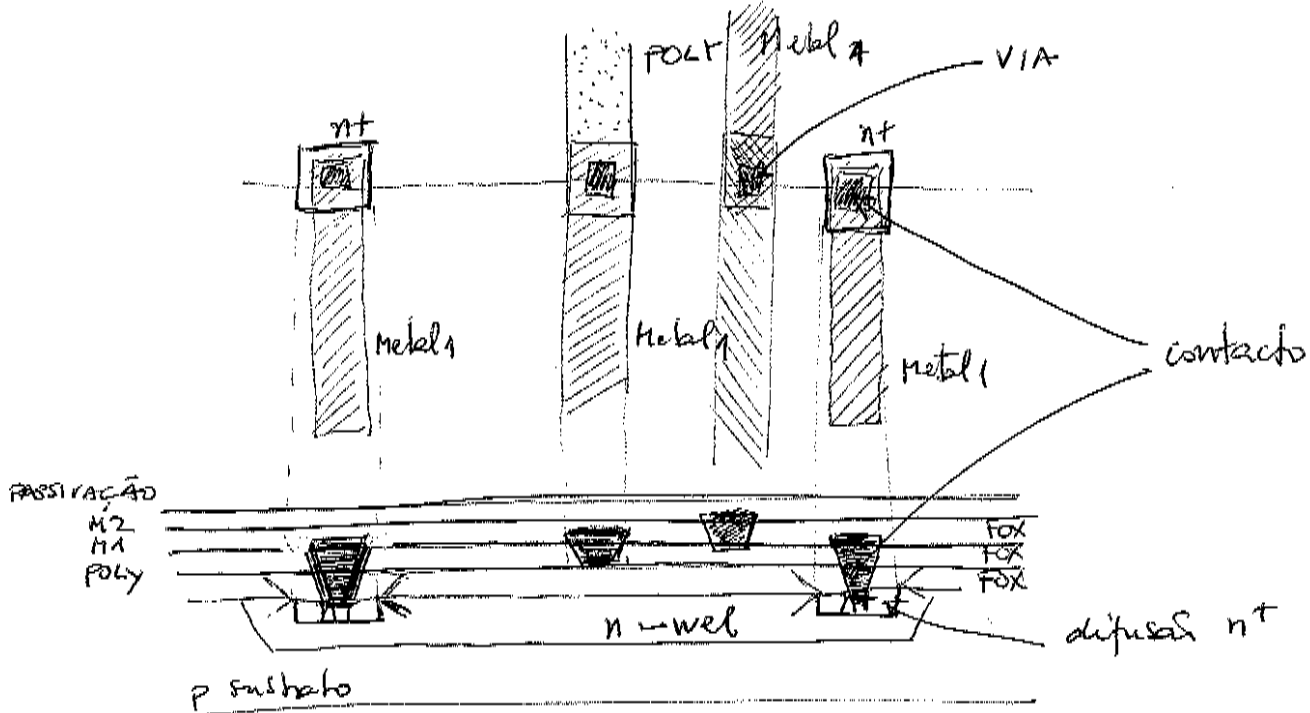


MICROELECTRÓNICA AULA 2

CAMADAS DE METAL , CAMADA DE POLISILÍCIO , REGIÃO ATIVA TIPO P E N. LAYOUT DO MOSFET

Camadas de metal - utilizadas essencialmente para fazer ligações

Camada de polissilício -
 | ligações porta dos MOSFETS
 | Condensadores

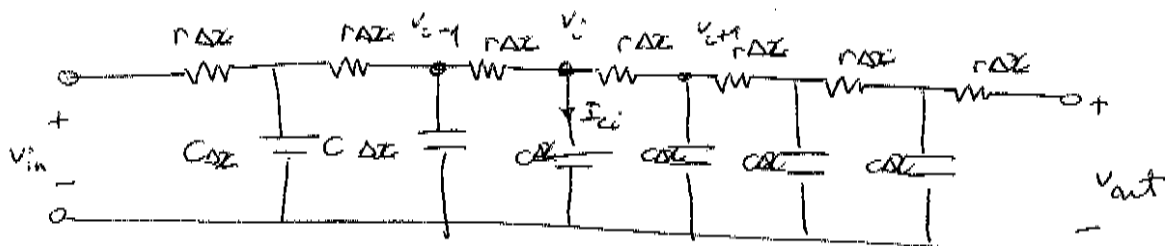


não importante para evitar dióxido de silício

no caso de se fazer uma ligação ao substrato



As linhas de metal e de polissilício têm capacitâncias parasitas para o substrato (e entre elas) e resistência. Podem ser modelizadas por um circuito RC distribuído:



$$I_{ci} = C_{AZE} \frac{dV_i}{dt} = I_{in} - I_o$$

$$= \frac{V_{i-1} - V_i}{R_{AZE}} - \frac{V_i - V_{i+1}}{R_{AZE}}$$

$$rc \frac{dv_i}{dt} = \frac{(v_{i-1} - v_i) - (v_i - v_{i+1})}{\Delta L^2}$$

Lim $\Delta L \rightarrow 0$ $rc \frac{dv_i}{dt} = \frac{\partial^2 v}{\partial x^2}$ eq da difusão

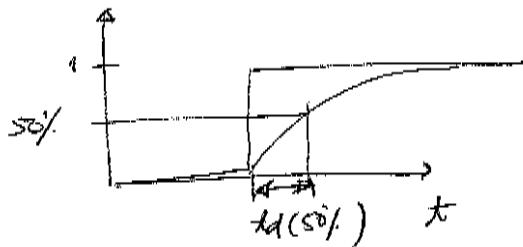
É possível encontrar uma constante de tempo τ dominante para

$$\tau = rc (\Delta x)^2 \frac{N(N+1)}{2}$$

onde $\Delta x = \frac{l}{N}$

com $\Delta x \rightarrow \infty \Rightarrow N \rightarrow \infty$ vem $\tau = \frac{rc l^2}{2}$ = $\frac{(rl)(cl)}{2} = \frac{RC}{2}$

o tempo de propagação t_d (50%) $\approx 0.35 RC$ (e não $0.69 RC$)



Exemplos

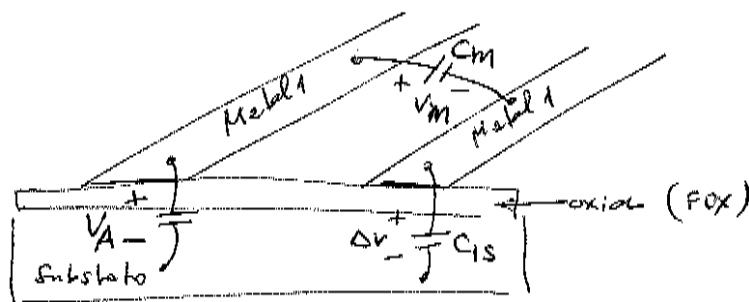
Calcular o tempo de propagação em condutores de Metal 1 de comprimento $l = 10 \text{ mm}$ e largura $w = 3 \mu\text{m}$

$$R_{\text{Metal 1}} = 0.06 \Omega/\square \quad R = 0.06 \times \frac{10 \times 10^3 \mu\text{m}}{3 \mu\text{m}} = 200 \Omega$$

$$C_{\text{Metal 1}} = 26 \times 10^{-18} \text{ F}/\mu\text{m}^2 \quad C = \frac{26 \times 10^{-18} \text{ F}}{\mu\text{m}^2} \times 10^4 \mu\text{m} \times 3 \mu\text{m} = 780 \text{ fF}$$

Logo $t_d = 0.35 RC = 0.35 \times 200 \times 780 \times 10^{-15} = \underline{\underline{55 \text{ ps}}}$

Cross Talk



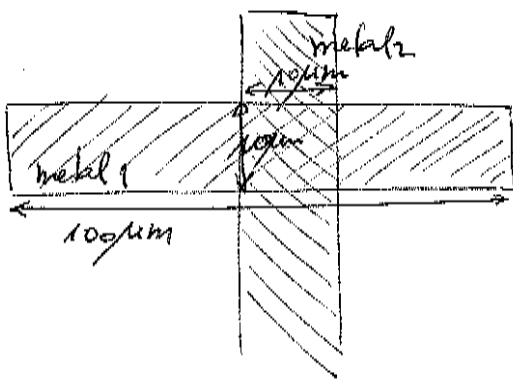
$$\left| \begin{array}{l} V_A = V_m + \Delta V \\ Q = C_m V_m = C_{1s} \Delta V \end{array} \right| \quad \left| \begin{array}{l} V_A = \frac{Q}{C_m} + \Delta V \\ V_A = \frac{C_{1s}}{C_m} \Delta V + \Delta V \end{array} \right.$$

$$V_A = \left(\frac{C_{15}}{C_m} + 1 \right) \Delta V = \frac{C_m + C_{15}}{C_m} \Delta V$$

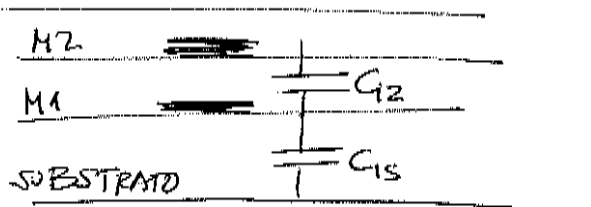
$$\Delta V = \frac{C_m}{C_m + C_{15}} V_A$$

Exemplo

Calcular a variação de tensão na pista de metal 1 quando na pista de metal 2 a tensão varia de 0 para 5V



seccao transversal



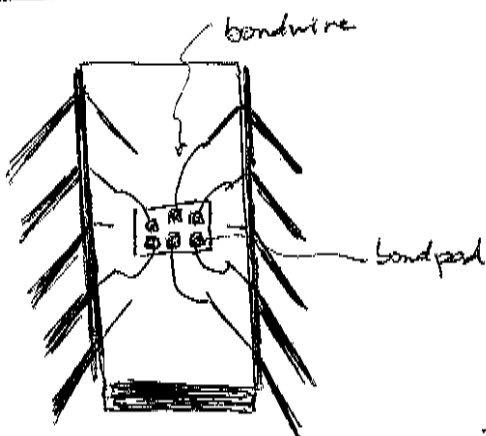
$$\Delta V = \frac{C_{12}}{C_{12} + C_{15}} \times 5V$$

$$C_{12} = \frac{38 \times 10^{-18} \text{ F}}{\mu\text{m}^2} \times \underbrace{(10 \mu\text{m})^2}_{\text{area}} + \frac{109 \times 10^{-18} \text{ F}}{\mu\text{m}} \times \underbrace{40 \mu\text{m}}_{\text{perimetro}} = 8 \text{ fF}$$

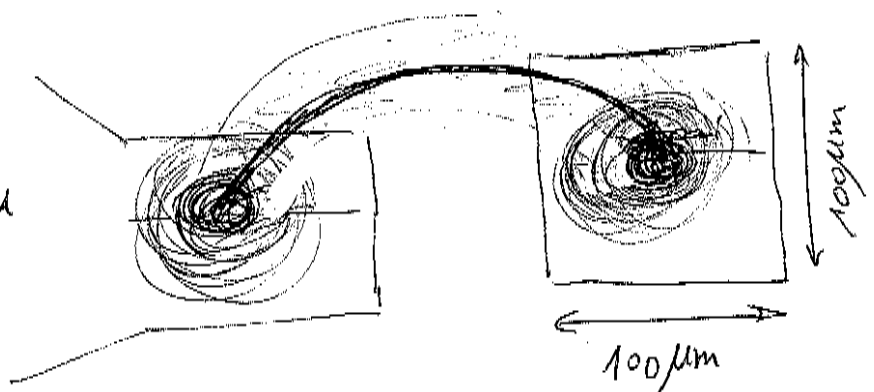
$$C_{15} = \frac{26 \times 10^{-18} \text{ F}}{\mu\text{m}^2} \times \underbrace{10 \mu\text{m} \times 100 \mu\text{m}}_{\text{area}} + \frac{82 \times 10^{-18} \text{ F}}{\mu\text{m}} \times \underbrace{220 \mu\text{m}}_{\text{perimetro}} = 44 \text{ fF}$$

$$\Delta V = \frac{8}{8 + 44} \times 5V = 0.8V$$

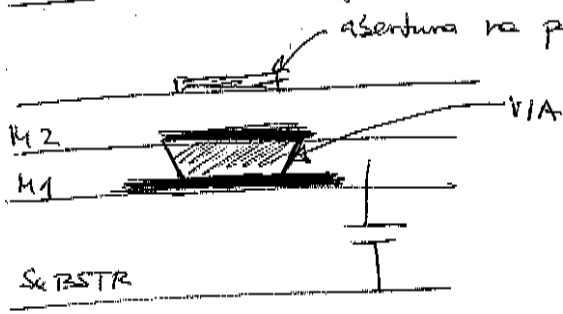
BOND PADS E BOND WIRES



Amplificas



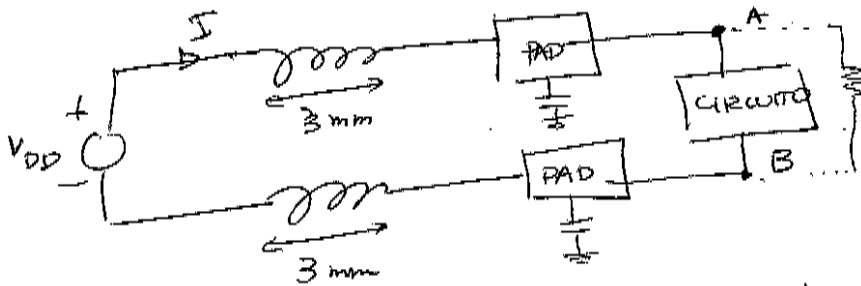
Cálculo da capacitância de 1 bond pad



$$C_{IS} = \frac{26 \times 10^{-15} \text{ F}}{\mu\text{m}^2} \times \underbrace{(100 \mu\text{m})^2}_{\text{área}} + \frac{82 \times 10^{-15} \text{ F}}{\mu\text{m}} \times 400 \mu\text{m} \text{ perímetro} = 0.3 \text{ pF} \leftarrow$$

Capacitância negligível: cause um circuito RC com a impedância de saída

BONDWIRE $L = 1 \text{ nH/mm}$

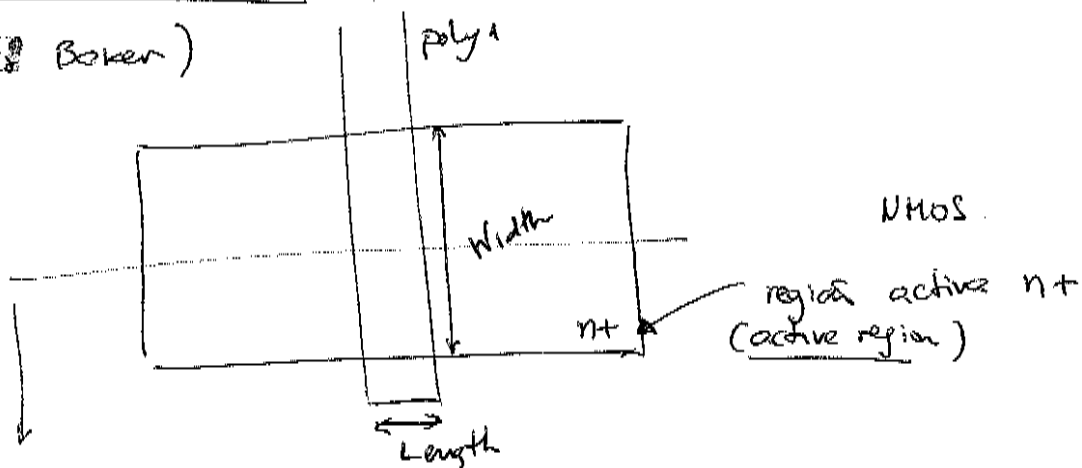


$$V_B = L \frac{dI}{dt} = 3 \text{ nH} \frac{50 \text{ nA}}{3 \text{ ns}} = 50 \text{ mV}$$

Calcular a variação de tensão no ponto B (A) qdo a corrente I varia 50 nA em 3 ns

LAYOUT DO MOSFET

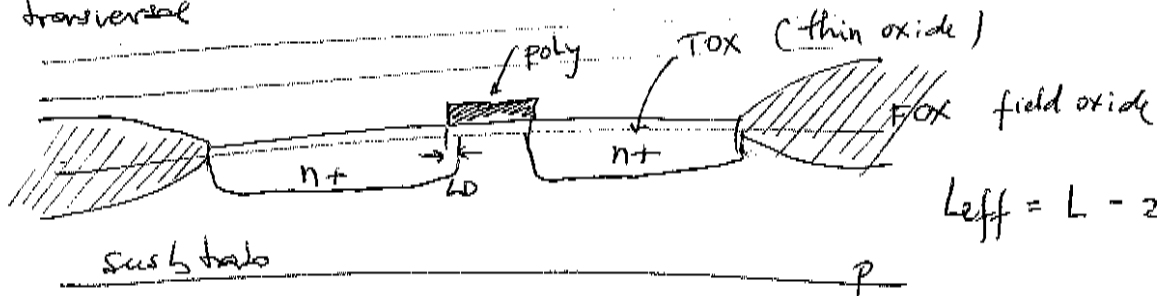
(Figure 4.8 Boker)



NMOS

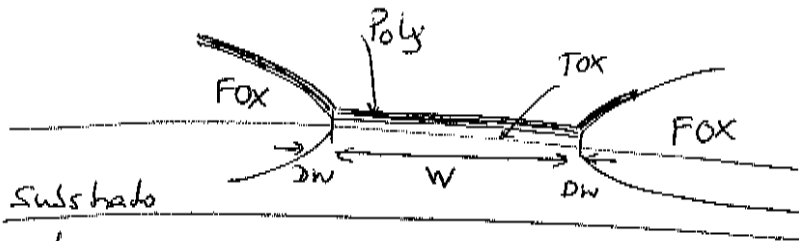
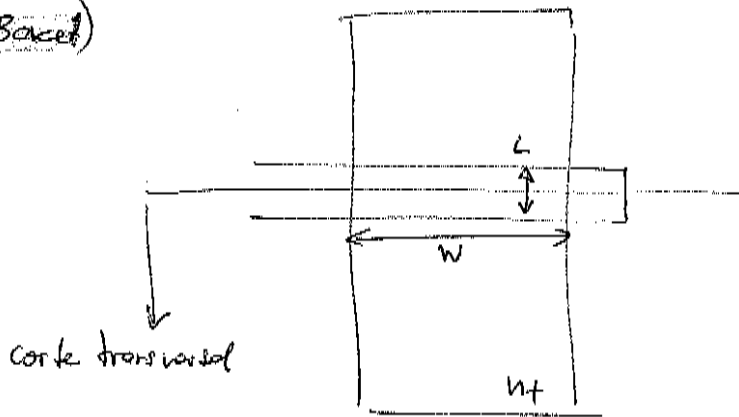
Cross section

Seção transversal



$$L_{eff} = L - 2LD$$

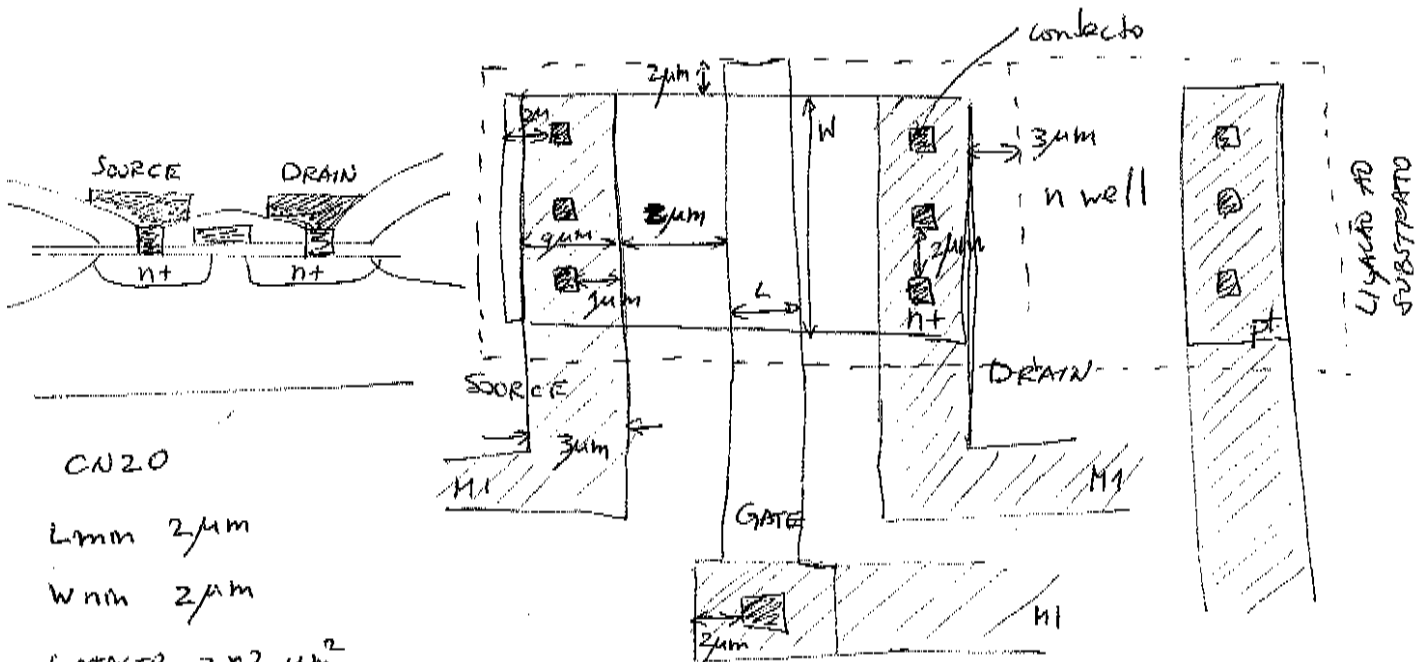
(Figura 4.11. Baccet)



$$W_{eff} = W + 2DW$$

Este efeito chama-se BIRD'S BEAK

REGRAS DE LAYOUT DO MOSFET (NMOS)



- CN20
- Lmm 2µm
- Wmm 2µm
- CONTACTO 2x2µm²
- ACTIVE CONTACT TO GATE 2µm
- POLY OVERLAP 2µm
- ACTIVE OVRLAP 2µm
- VIA 2x2µm²
- METAL 2 OVERLAP 2µm
- METAL 1 OVERLAP 1µm